

02-14-02

A

Docket No. 5018/ISM/CORE MCVD

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application
 Commissioner of Patents and Trademarks
 Washington, D.C. 20231

1002 U.S. PTO
 10/07/02
 02/11/02



Re: Inventor(s): Avi TEPMAN and Lawrence Chung-lai LEI
 Title: VARIABLE FLOW DEPOSITION APPARATUS AND METHOD IN SEMICONDUCTOR SUBSTRATE
 PROCESSING

Transmitted herewith is the patent application identified above, including:

- Specification, claims and abstract, totaling 29 pages.
- Drawings totaling 4 pages, Formal Informal.
- Executed Declaration and Power of Attorney.
- Assignment of the invention to **Applied Materials, Inc.**
- Assignment Recordation Cover Sheet
- Information Disclosure Statement (37 CFR 1.98)

| FEE CALCULATION | | | | | |
|--------------------|--------------|-------------------------|--------------|----------|------------------|
| Fee Items | Claims Filed | Included With Basic Fee | Extra Claims | Fee Rate | Total |
| Total Claims | 51 | -20= | 31 | X\$18.00 | \$ 558.00 |
| Independent Claims | 6 | -3= | 3 | X\$84.00 | \$ 252.00 |
| Basic Filing Fee | | | | \$740.00 | \$ 740.00 |
| TOTAL FEES | | | | | \$1550.00 |

- The Commissioner is hereby authorized to charge \$1550.00 to Deposit Account No. 50-1074.
- The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074. A duplicate copy of this transmittal is enclosed.
- Please address all future correspondence to:

PATENT COUNSEL
APPLIED MATERIALS, INC.
 Legal Affairs Department
 P.O. BOX 450A
 Santa Clara, CA. 95052

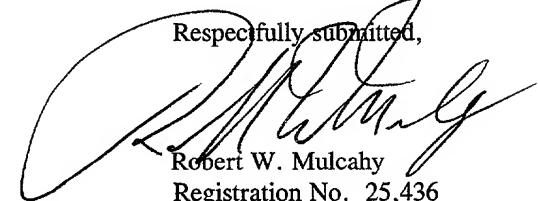
I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner of Patents and Trademarks, Washington, D.C. 20231.

Express Mail Receipt No. EV049834328US

Date of Deposit 2-11-02

Signature Ben Mulcahy

Respectfully submitted,



Robert W. Mulcahy
 Registration No. 25,436